

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



re application of:

Tzeng
Serial No: 09/501,114
Filed: February 10, 2000
For: Method of Plasma Enhanced
 Chemical Vapor Deposition
 of Diamond

Group Art Unit: 1762
Examiner: Wesley D. Markham
Docket No.: 220101-1010

#13C
Wesley D. Markham
10/23/02

RESPONSE TO OFFICE ACTION

Assistant Commissioner for Patents
 Washington, D.C. 20231

Sir:

The Office Action mailed June 27, 2002 (Paper No. 11) has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.

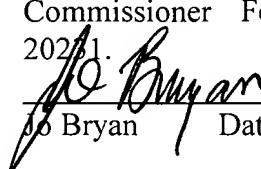
RECEIVED
 OCT 24 2002
 TC 1700

AUTHORIZATION TO DEBIT ACCOUNT

It is not believed that extensions of time or fees for net addition of claims are required, beyond those, which may otherwise be provided for in documents accompanying this paper. However, in the event that additional extensions of time are necessary to allow consideration of this paper, such extensions are hereby petitioned under 37 C.F.R. § 1.136(a), and any fees required therefor (including fees for net addition of claims) are hereby authorized to be charged to deposit account no. 20-0778.

CERTIFICATE OF MAILING (37 CFR 1.8)

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope to the: Assistant Commissioner For Patents, Washington, D.C. 20231.


 Jo Bryan Date: Oct. 14, 2002

10/23/2002 MBERHE 00000098 09501114

01 FC:2202
02 FC:220154.00 OP
84.00 OP